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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

 Form PTO-1449 (Modified)
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COMPLETE IF KNOWN

Application Number	09/888,002
Confirmation Number	9049
Filing Date	June 21, 2001
First Named Inventor	Whonchee Lee
Group Art Unit	3723
Examiner Name	Dung V. Nguyen
Attorney Docket No.	108298515US3

Sheet 1 of 5

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
DVN		U.S. Application No. 09/651,779 ✓ (Atty. Docket No. 10829.8515US)		Moore	Filed 08/30/2000	
		U.S. Application No. 09/651,808 ✓ (Atty. Docket No. 4373US)		Chopra et al.	Filed 08/30/2000	
		U.S. Application No. 09/653,392 ✓ (Atty. Docket No. MTI-31044)		Chopra et al.	Filed 08/31/2000	
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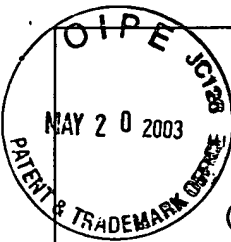
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		NUMBER	Kind Code (if known)			
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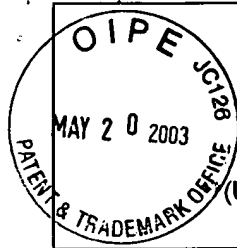
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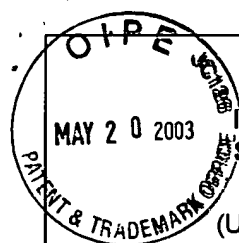
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		Office	NUMBER	Kind Code (if known)				
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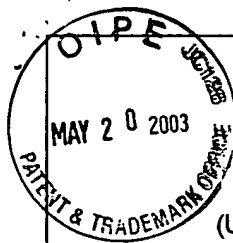
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T
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DVN	AA	U.S. Application No. 10/090,869 (Atty. Docket No. 10829.8544US)		Moore et al.	Filed 03/04/2002	

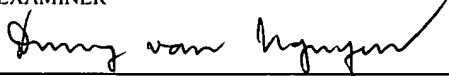
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